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(54) Title: SILICON-SELECTIVE DRY ETCH FOR CARBON-CONTAINING FILMS

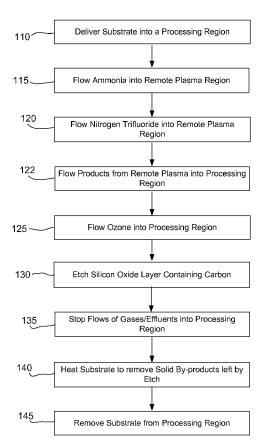


FIG. 1

(57) Abstract: A method of etching silicon-and-carbon-containing material is described and includes a SiConiTM etch in combination with a flow of reactive oxygen. The reactive oxygen may be introduced before the SiConiTM etch reducing the carbon content in the near surface region and allowing the SiConiTM etch to proceed more rapidly. Alternatively, reactive oxygen may be introduced during the $SiConi^{TM}$ etch further improving the effective etch rate.



CA, CH, CL, CN, CO, CR, CU, CZ, DE, DK, DM, DO, DZ, EC, EE, EG, ES, FI, GB, GD, GE, GH, GM, GT, HN, HR, HU, ID, IL, IN, IS, JP, KE, KG, KM, KN, KP, KR, KZ, LA, LC, LK, LR, LS, LT, LU, LY, MA, MD, ME, MG, MK, MN, MW, MX, MY, MZ, NA, NG, NI, NO, NZ, OM, PE, PG, PH, PL, PT, RO, RS, RU, SC, SD, SE, SG, SK, SL, SM, ST, SV, SY, TH, TJ, TM, TN, TR, TT, TZ, UA, UG, US, UZ, VC, VN, ZA, ZM, ZW.

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A. CLASSIFICATION OF SUBJECT MATTER

H01L 21/3065(2006.01)i, G03F 7/42(2006.01)i, B44C 1/22(2006.01)i

According to International Patent Classification (IPC) or to both national classification and IPC

B. FIELDS SEARCHED

Minimum documentation searched (classification system followed by classification symbols)

H01L 21/3065; H01L 21/302; B08B 7/00; H01L 21/4763; H01L 21/3205

Documentation searched other than minimum documentation to the extent that such documents are included in the fields searched Korean utility models and applications for utility models

Japanese utility models and applications for utility models

Electronic data base consulted during the international search (name of data base and, where practicable, search terms used) eKOMPASS(KIPO internal) & Keywords: etch, byproduct, remove, sublimation

C. DOCUMENTS CONSIDERED TO BE RELEVANT

Category*	Citation of document, with indication, where appropriate, of the relevant passages	Relevant to claim No.
A	US 7488688 B2 (CHUNG SEUNG-PIL et al.) 10 February 2009 See abstract; column 8, line 15-column 9, line 49; claims 1,3,5.	1-15
A	US 5888906 A (SANDHU; GURTEJ S. et al.) 30 March 1999 See column 3, line 41-column 6, line 3; claims 1-2,19-20,25; figures 1-3.	1-15
A	US 6796314 B1 (GRAFF; WESLEY P.) 28 September 2004 See column 2, line 49-column 6, line 6; claims 1,9,13-14.	1-15
A	US 2005-0181588 A1 (JEONG-HO KIM) 18 August 2005 See abstract;paragraphs [0022]-[0066];claims 1,2,6,11-15.	1-15

		Further documents are	listed in the	e continuation	of Box C.
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See patent family annex.

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Date of the actual completion of the international search

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INTERNATIONAL SEARCH REPORT

Information on patent family members

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Patent document cited in search report	Publication date	Patent family member(s)	Publication date
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